



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Kajiwara et al.  
Serial No. 09/874,174

Filed: June 4, 2001

For: CHEMICAL MECHANICAL  
POLISHING APPARATUS AND  
METHOD HAVING A RETAINING  
RING WITH A CONTOURED  
SURFACE

Art Unit: 3723

Examiner: MORGAN, Eileen P.  
Attorney Docket No. A-70092/RMA

Date: December 13, 2004

PETITION FOR EXTENSION OF TIME

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Pursuant to 37 C.F.R. 1.136(a), a petition for an extension of time of (1) one month is hereby requested to respond to the Office Action mailed August 12, 2004.

The Commissioner is hereby authorized to charge any additional fees or credit any overpayment to Deposit Account No. 50-2319 (Order No. A-70092/RMA).

Respectfully submitted,

DORSEY & WHITNEY LLP

By:

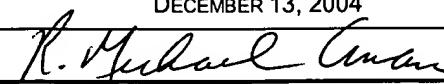
  
R. Michael Ananian  
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CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to COMMISSIONER FOR PATENTS, P.O. Box 1450, Alexandria, VA 22313-1450, on this date:

DECEMBER 13, 2004

Typed or printed name	R. MICHAEL ANANIAN	Signature	
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